

Applicant(s): Kiyoshi Mita
SEMICONDUCTOR DEVICE AND METHOD OF
MANUFACTURING THE SAME



FIG.1A



$\frac{10}{S}$

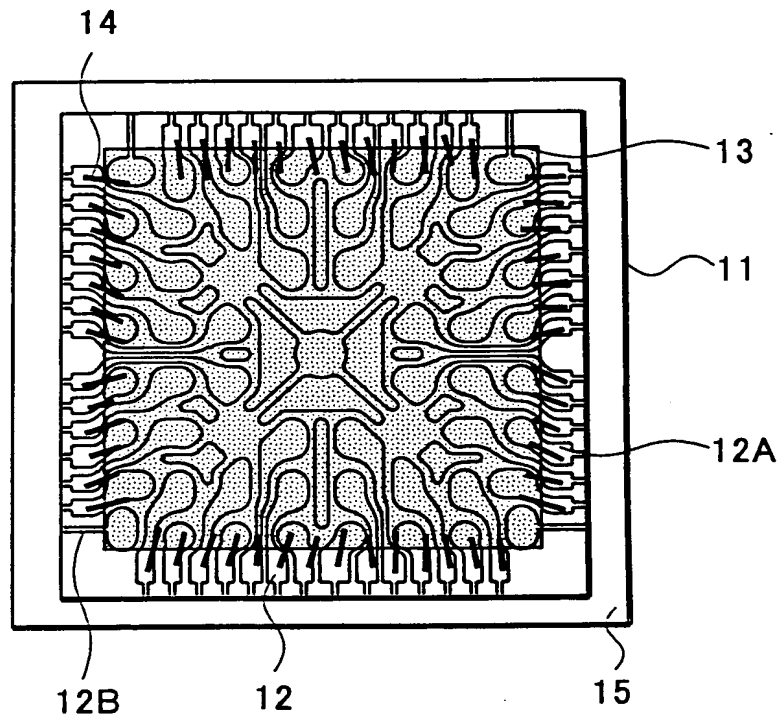


FIG.1B

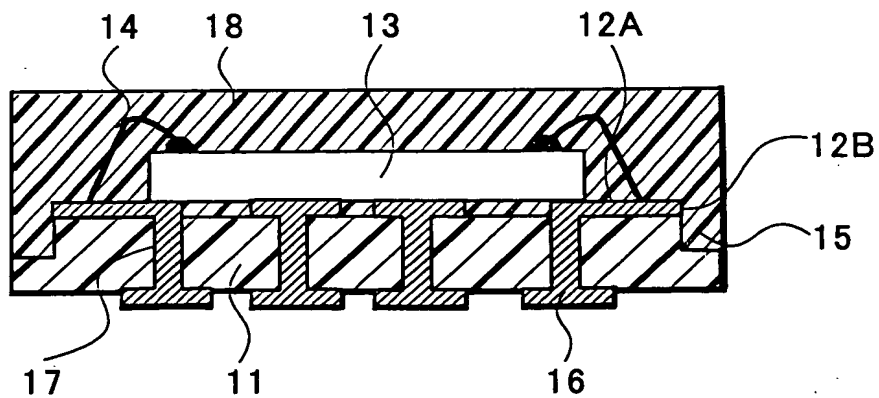


FIG.2A

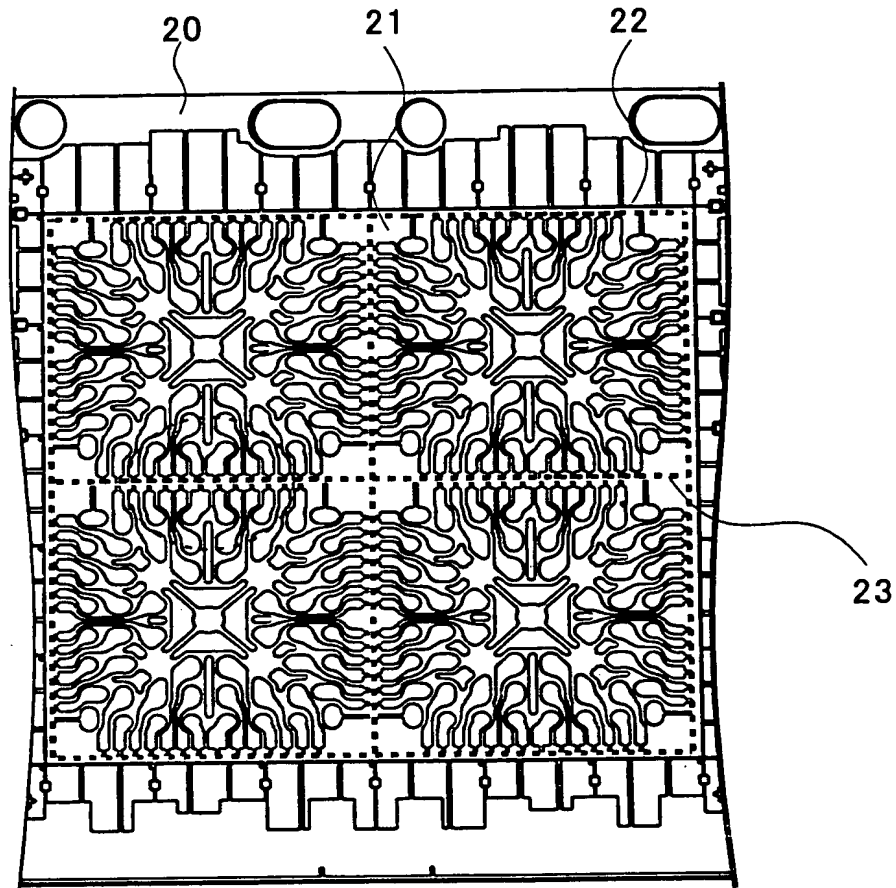


FIG.2B

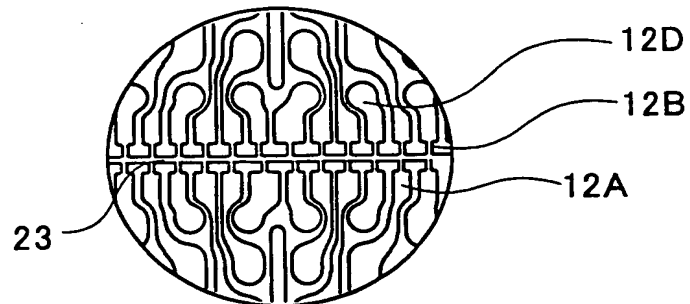


FIG.2C

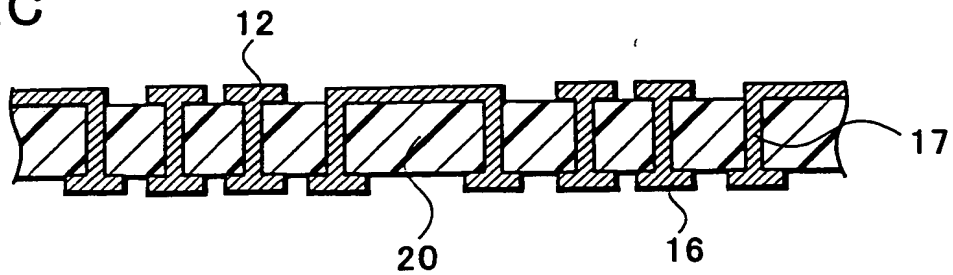


FIG.3A

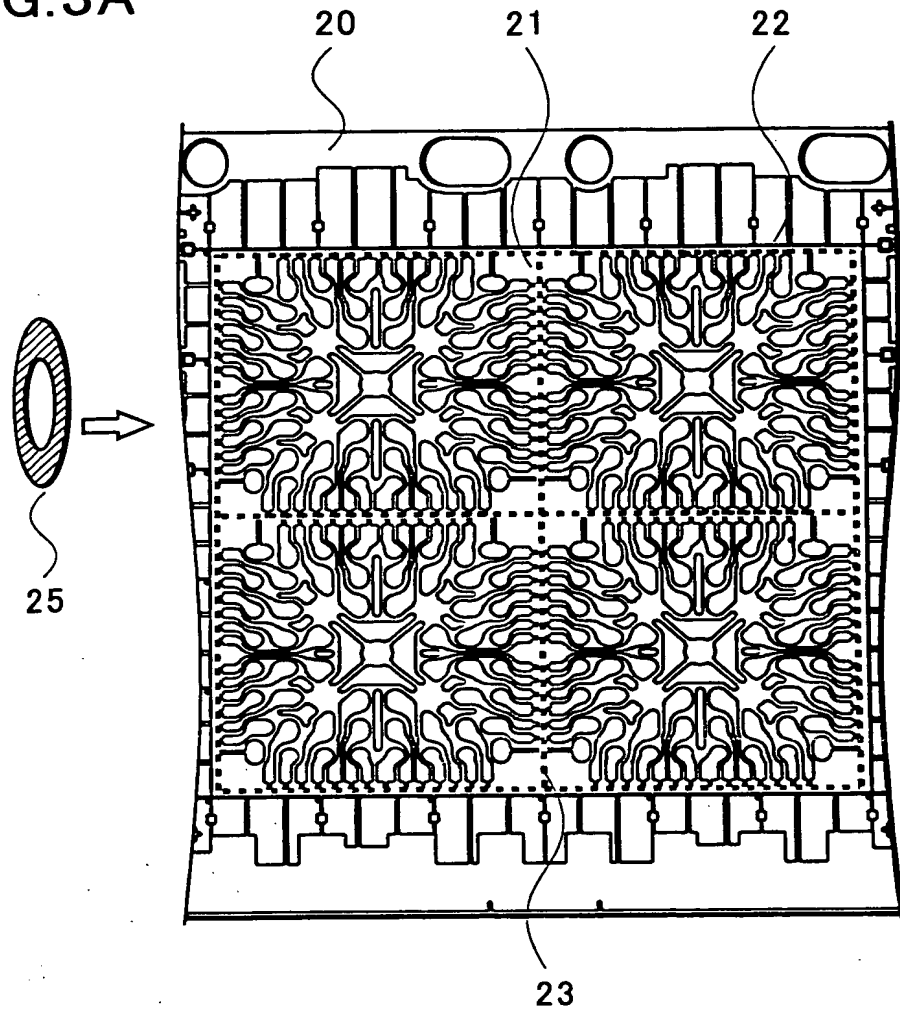


FIG.3B

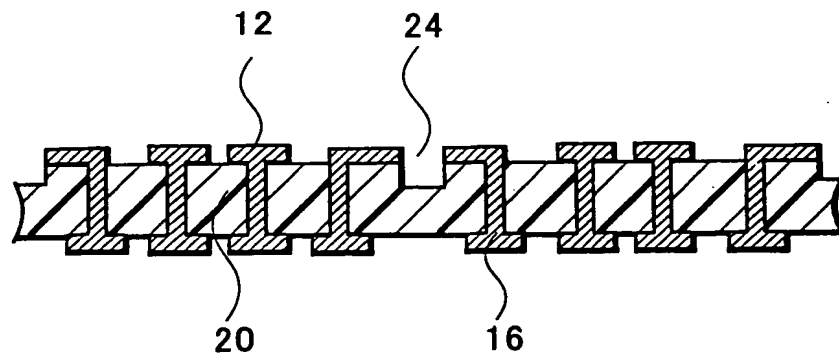


FIG.4

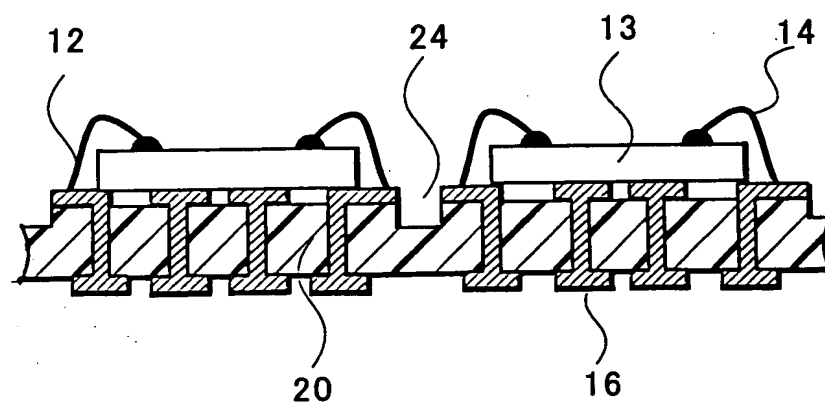


FIG.5

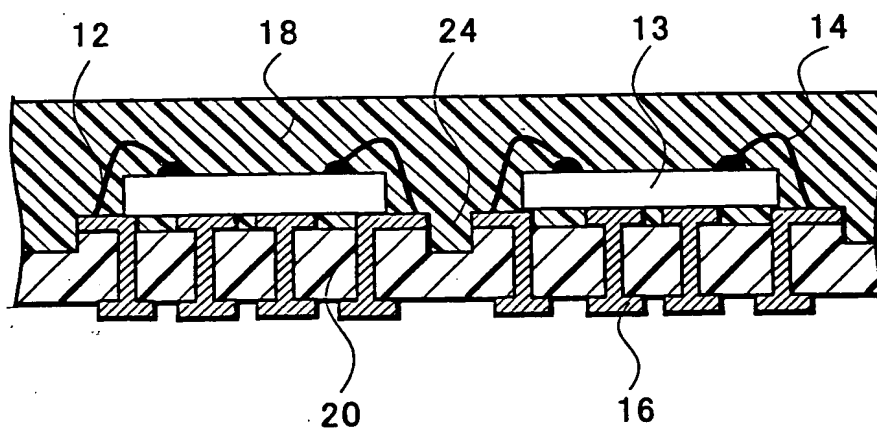


FIG.6

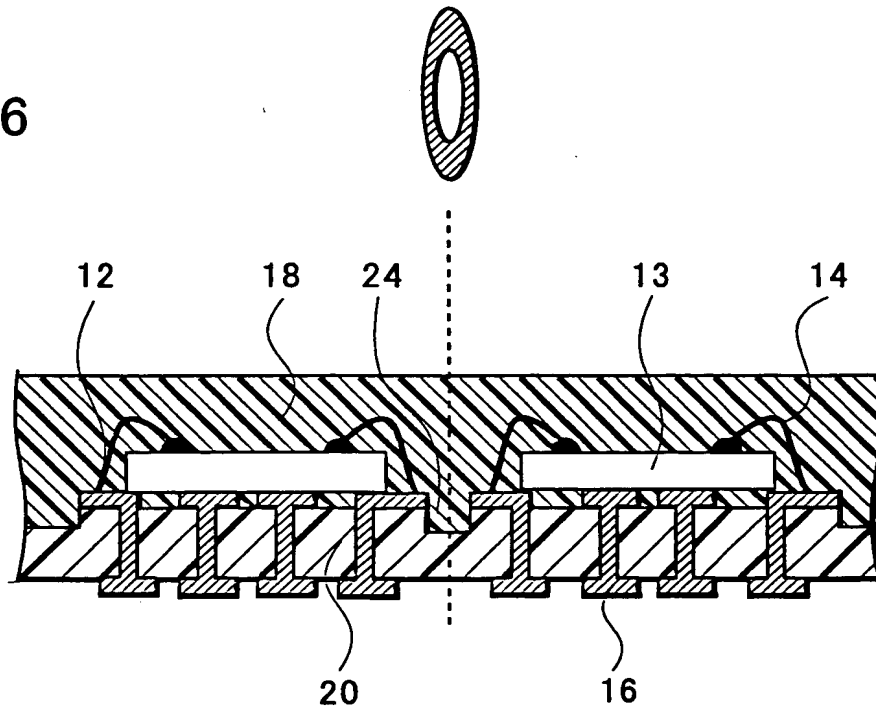


FIG.7

